

# PATENT ABSTRACTS OF JAPAN

(11)Publication number : 04-291916

(43)Date of publication of application : 16.10.1992

(51)Int.Cl.

H01L 21/205  
C30B 25/16

(21)Application number : 03-056931

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(22)Date of filing : 20.03.1991

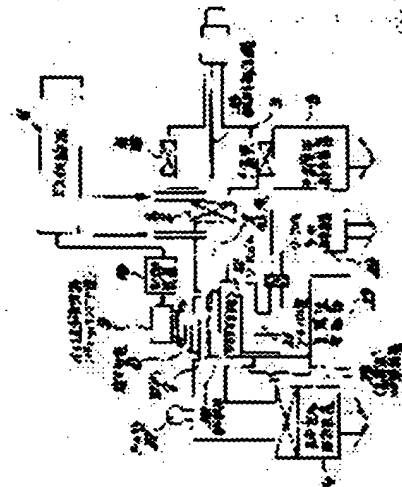
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## (54) METHOD AND APPARATUS FOR VAPOR GROWTH

### (57)Abstract:

PURPOSE: To form a thin film as an atomic layer on a specimen.

CONSTITUTION: In a state that a specimen 7 arranged inside a reaction chamber 1 is exposed to a raw-material gas introduced from a gas supply source 6, the specimen 7 is irradiated with pulse light by using a pulse-light irradiation light source 9. Thereby, a thin film as a monoatomic layer or as a layer of several atoms is grown at each irradiation operation.



## LEGAL STATUS

[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]